

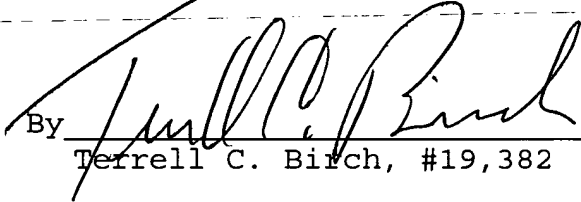
- ☐ Petition for () month(s) extension of time pursuant to 37 C.F.R. §§ 1.17 and 1.136(a). \$0.00 for the extension of time.
- ☒ No fee is required.
- ☐ Check(s) in the amount of \$0.00 is(are) enclosed.
- ☐ Please charge Deposit Account No. 02-2448 in the amount of \$0.00. This form is submitted in triplicate.


If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies, to charge payment or credit any overpayment to Deposit Account No. 02-2448 for any additional fees required under 37 C.F.R. §§1.16 or 1.17; particularly, extension of time fees.

Respectfully submitted,

BIRCH, STEWART, KOLASCH & BIRCH, LLP

By


Terrell C. Birch, #19,382


TCB/CMV/jdm
0397-0404P

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Attachment(s)

(Rev. 09/30/02)



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11B
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BOX AF
REPLY UNDER
37 C.F.R. § 1.116
EXPEDITED PROCEDURE

PATENT
0397-0404P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: H. TAKEUCHI et al. Conf.: 4024
Appl. No.: 09/541,089 Group: 1762
Filed: March 31, 2000 Examiner: M. PADGETT
For: PLASMA PROCESSING METHOD

REPLY AFTER FINAL UNDER 37 C.F.R. § 1.116

BOX AF

Assistant Commissioner for Patents
Washington, DC 20231

February 6, 2003

Sir:

In reply to the Office Action mailed November 7, 2002, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please amend the claims as follows:

- 500
C₁
1. (Twice Amended) A plasma processing method comprising:
supporting a substrate to be opposed to an electrode;
setting the plasma processing gas to pressure P(Torr) where P(Torr) satisfies the following relationship
$$2 \times 10^{-7} (\text{Torr/Hz}) \times f(\text{Hz}) \leq P(\text{Torr}) \leq 500 (\text{Torr})$$